

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 241330US6YA		SERIAL NO. 10/650,729	
LIST OF REFERENCES CITED BY APPLICANT <i>JUL 1 9 2005</i>		APPLICANT Chung-Peng HO, et al.					
		FILING DATE August 29, 2003		GROUP 1756			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
DP	AA 5,986,742	11/16/99	Straaijer et al.				
DP	AB 2002/0163629	11/7/02	Switkes et al.				
	AC						
	AD						
	AE						
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	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY		TRANSLATION YES NO		
AO							
AP							
AQ							
AR							
AS							
AT							
AU							
AV							
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
DP	AW	Owen et al., "1/8 μm optical lithography," Journal of Vacuum Science and Technology, B 10(6), 3032-3036 (1992).					
DP	AX	Switkes et al., "Immersion lithography at 157 nm," Journal of Vacuum Science and Technology, B 19(6), 2353-2356 (2001).					
DP	AY	Hoffnagle et al., "Liquid immersion deep-ultraviolet interferometric lithography," Journal of Vacuum Science and Technology, B 17(6), 3306-3309 (1999).					
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner <i>Denis</i>				Date Considered 09/17/2005			

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.